



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kazuhiko FUKAZAWA et al.

Group Art Unit: 2829

Application No.: 10/807,262

Examiner: J. Nguyen

Filed: March 24, 2004

Docket No.: 119216

For: SUBSTRATE INSPECTION SYSTEM, SUBSTRATE INSPECTION METHOD, AND
SUBSTRATE INSPECTION APPARATUS

REQUEST FOR RECONSIDERATION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the July 25, 2005 Office Action, Applicants request reconsideration of this application. Claims 1-17 are pending.

Claims 1-17 stand rejected under 35 U.S.C. §102(e) over U.S. Patent No. 6,790,287 to Shiga et al. This rejection is respectfully traversed.

Shiga et al. does not disclose or suggest the combinations of features recited in the independent claims of this application. Shiga et al. discloses that an inspecting unit 30 can have different types of inspection devices 32-35, including a macro defect inspection device 35. See, for example, col. 5, lines 26-31 and col. 6, lines 29-42. While Shiga et al. teaches that the different inspection devices 32-35 can be used in different orders, Shiga et al. does not disclose or suggest making any determinations regarding subsequent inspections based upon the results of the inspection made by the macro defect inspection device 35.